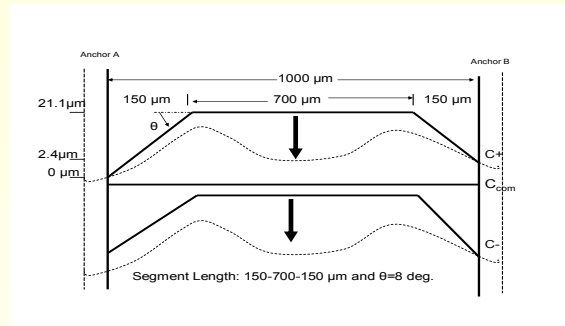


Micro Electromechanical Capacitive Strain Sensor

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A new MEMS Capacitive Strain Sensor has been developed that:

- can measure large values of strain
- is linear in the range of 600 - 3000 microstrain
- is compatible with off-the-shelf electronics
- has low power consumption – 30 mW
- can be integrated with CMOS electronics
- is compatible with wireless transmission systems
- has low temperature dependence for outdoor use
- has low noise and turn-on drift
- is easy to fabricate (8 step, 2 mask process)
- is useful in Structural Health Monitoring applications.



Granted three U.S. Patents – 7,380,461 (6/3/2008), 7,603,910 (10/20/2009), and 7,836,776 (11/23/2010)